

DOCKET: HSJ920040257US1 (HITG.103PA)

US Department of Commerce
Patent & Trademark OfficeRecordation Form Cover Sheet
PATENTS ONLY

To the Honorable Commissioner of Patents and Trademarks: Please record the attached original documents or copy thereof.

1. Name of conveying party(ies):

David P. Druist
Aron Pentek

2. Name and address of receiving party(ies):

Name: Hitachi Global Storage
Technologies Netherlands B.V.

Street Address:

Locatellikade 1
Parnassustoren
1076 AZ Amsterdam
The NetherlandsAdditional name(s) of conveying
party(ies) attached ☐ Yes ☒ NoAdditional name(s) & address(es) attached?
☐ Yes ☒ No

3. Nature of conveyance:

XX Assignment

Execution Date(s): January 5, 2005; and January 7, 2005

4. Application number(s) or patent number(s):

If this document is being filed together with a new application, the execution date of the application is:

A. Patent Application No.(s)

B. Patent No.(s)

11,037,405 filed January 18, 2005

Additional numbers attached? ☐ Yes ☒ No5. Name and address of party to whom
correspondence concerning document
should be mailed:

Name: David W. Lynch

Customer No.
51298Address: CRAWFORD MAUNU PLLC
1270 Northland Drive
Suite 390
St. Paul MN 551206. Total Number of applications and patents
involved: One

7. Total fee (37 CFR 3.41).....\$ 40.00

☐ EnclosedXX Authorized to be charged to deposit
account

8. Deposit Account Number: 50-2587

9. Statement and signature.

To the best of my knowledge and belief, the foregoing information is true and correct and any attached copy is a true copy of the original document.

Date

3/10/05

David W. Lynch

Total number of pages including cover sheet, attachments, and document: 2

CH \$40.00 602687 11037405

Docket: **HSJ920040257US1 (HITG.103PA)****ASSIGNMENT**INVENTOR
AND CITY

Whereas, I/we

(1) David P. Druist of 444 Saratoga Avenue, Apt. 17G, Santa Clara, CA 95050
(2) Aron Pentek of 1437 Corte De Rosa, San Jose, CA 95120

have invented certain improvements in

TITLE

Method For Protecting Write Head Coil During Write Pole Notching Using Ion Mill Resistant Mask Formed By Reactive Ion EtchingDATES THAT
INVENTORS
SIGNED THE
DECLARATION

and executed, respectively, a United States patent application therefore on

(1) 1/5/2005 (2) 1/7/2005

Whereas, **HITACHI GLOBAL STORAGE TECHNOLOGIES NETHERLANDS B.V.**, having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands (hereinafter called HITACHI), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefore;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to HITACHI, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the inventions set forth in said application to HITACHI, its successors and assigns; and we hereby agree that HITACHI may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by HITACHI.

CITY

(1) Signed at San JoseDavid P. Druist

SIGNATURE

DATE

on 1/5/2005, (MMDDYY), **David P. Druist**

INVENTOR

CITY

(2) Signed at San JoseAron Pentek

SIGNATURE

DATE

on 1/7/2005, (MMDDYY), **Aron Pentek**

INVENTOR